

Micro & Nanotechnology Laboratory

Cleanroom Equipment "Super-User" List

Anyone with questions or problems concerning the laboratory equipment listed below should contact the designated super-user shown below.

Everyone must be "checked out" by the appropriate super-user before they can use any of these tools without supervision.

Lab 205 -- Electron-Beam Lithography Lab

JEOL E-beam System	Edmond Chow
MII Imprint Lithography System	Marty Harris

Lab 209 -- Deposition Lab

Cooke Evaporator	Hal Romans
Cooke Sputter System	Hal Romans
CHA Evaporator	Hal Romans
NRC Evaporator	Hal Romans
Edwards Evaporator	Hal Romans
Lesker Sputter System	Hal Romans
Denton Optical Coater	Rohan Bambery

Lab 211 -- Optical Lithography Lab

Quintel Aligner	Marty Harris
Karl Suss Aligners	Marty Harris
GCA Wafer Stepper	Marty Harris
Fusion Flood Exposure System	Marty Harris
Fusion Deep-UV Exposure System	Marty Harris
Spinners (Headway EC-10, Solitec)	Marty Harris
Spinner (Headway PWM32)	Tony Giannopoulos

Lab 216 -- Dry Processing

STS ICP Deep Silicon Etch System	Yaguang Lian
STS PECVD System (Silicon Nitride)	Yaguang Lian
PlasmaLab ("Master/Slave") RIE System	Yaguang Lian
TI Planer Plasma System	Yaguang Lian
PlasmaTherm ICP RIE system	Yaguang Lian

Lab 222 -- NanoTaxy Lab

Atomate Carbon Nanotube CVD System	Albert Liao
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Lab 232 -- PECVD Lab

PlasmaLab PECVD System (Silicon Dioxide)	Yaguang Lian
PlasmaLab RIE System ("Freon RIE")	Yaguang Lian
ASM LPCVD System	Hal Romans
Verteq Wafer Spin Rinser/Dryer	Hal Romans
Cambridge NanoTech ALD System	Marty Harris

Lab 237 -- MEMS Lab

Oxidation/Diffusion/Anneal Furnaces	Hal Romans
FSM Film Stress Measurement System	Hal Romans
PDS Parylene Deposition System	Hal Romans
Jipelec Rapid Thermal Processor	Yaguang Lian
AG Heatpulse 610 Rapid Thermal Processor	Yaguang Lian
Xactix XeF2 Etching System	Yaguang Lian
Idonus HF Vapor Phase Etch System	Yaguang Lian
Tousimis Critical Point Dryer	Yaguang Lian

Lab 239 -- Large-Area Lithography Lab

Anvik Large-Area Lithography System	Marty Harris
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Lab 241 -- Inspection and Assembly Lab

Hitachi 4500 and 4800 FE SEMs	Edmond Chow
SPI Sputter Coater	Edmond Chow
Digital Instruments AFM	Edmond Chow
Hummer Sputter System	Hal Romans
Alpha-Step Profilometers	Yaguang Lian
Rudolph Focus Ellipsometer	Yaguang Lian
Veeco Optical Profiler	Marty Harris
NanoSpec 4000 Film Thickness Measurement	Marty Harris

Portable:

Alcatel Leak Detector	Hal Romans
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